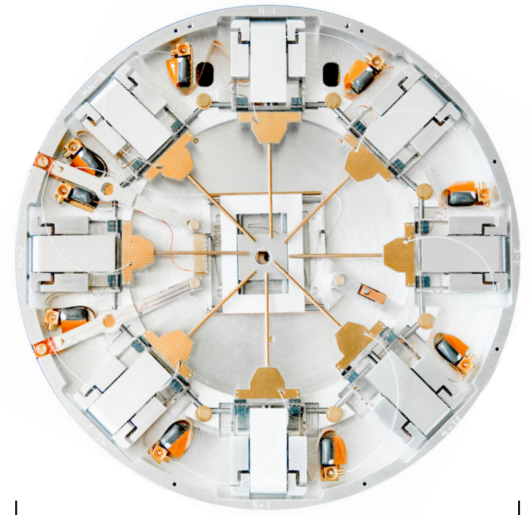
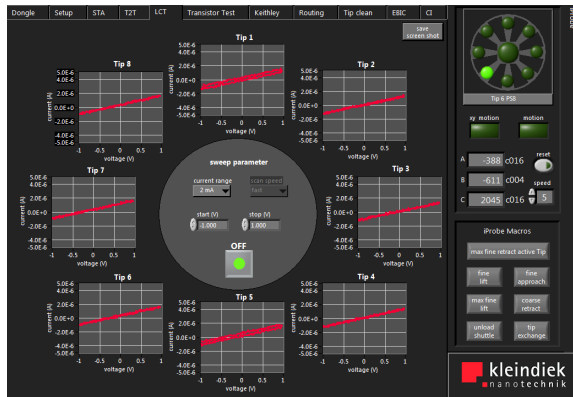


During Current Imaging, each of the eight probes can be biased and scanned over the sample surface, allowing for the acquisition of current flow images (CI) with sub-pA resolution. In this example, the correlation of SEM and CI is used to locate leakages in 22 nm SRAM devices. ^



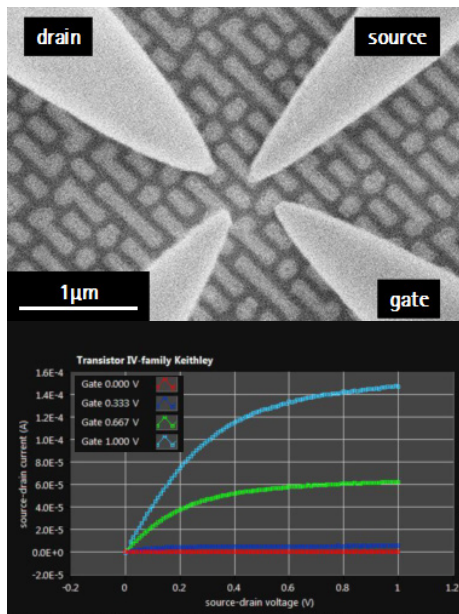
140 mm

Prober Shuttle with eight probes



### LCT

The Live Contact Tester serves as an 'electric eye' - it visualizes the contact between tip and substrate.

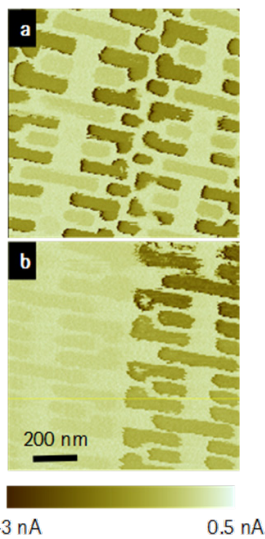
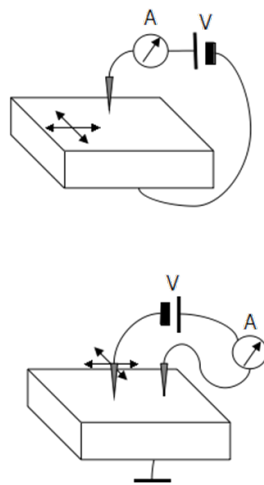
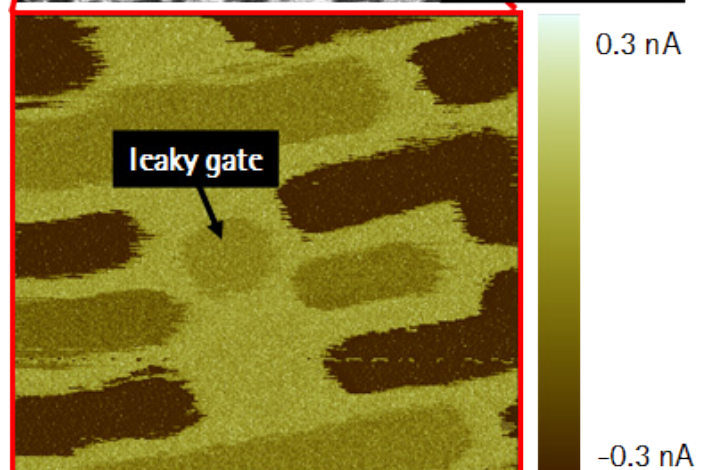
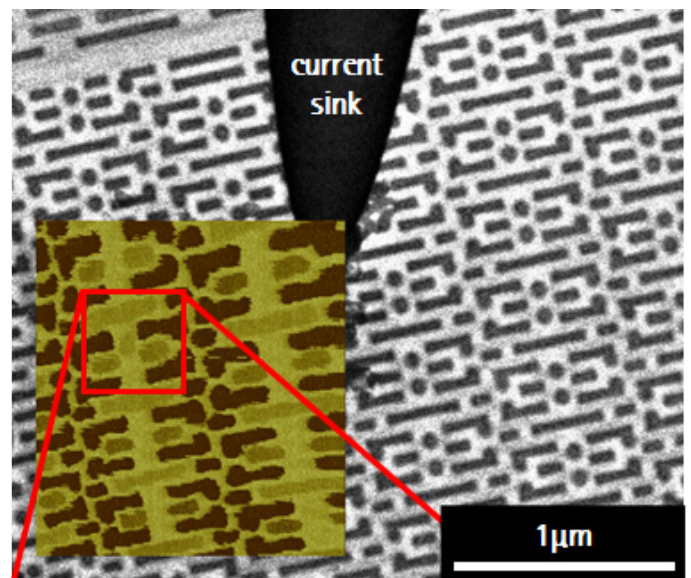


### Failure Localization

Using the probes and with the help of the Advanced Probing Tools the needles can be landed on the contacts. The resulting current-voltage curves (IVCs) yield insight into the device's condition.

### Leaky Gate

With the help of the CI technique, a leaky gate could be identified:



### Current paths

The CI module allows flexibility in defining the current path. In combination with the variation in the current source's bias voltage, this feature can be used to differentiate structures on the sample as well as for identifying faults.

### Further information

- Find our more on our website: [www.kleindiek.com](http://www.kleindiek.com)